



Docket No.: M4065.0227/P227
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Tongbi Jiang et al.

Application No.: 09/652,216

Confirmation No.: 2311

Filed: August 30, 2000

Art Unit: 2813

For: METHOD AND APPARATUS FOR
REDUCING SUBSTRATE BIAS VOLTAGE
DROP

Examiner: E. T. Pert

STATUS INQUIRY

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

It is respectfully requested that the attorney named below be advised of the status of the above-identified application. Please advise us of when we might expect to receive an Office Action from the Patent and Trademark Office.

Dated: April 21, 2004

Respectfully submitted,

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